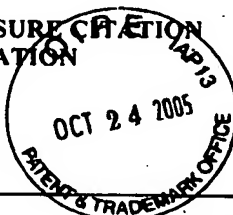


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					081468-0308582		10/792,267	
					Applicant(s)			
					Klaus SIMON			
Form PTO-1449					Filing Date		Group Art Unit	
					March 4, 2004		1762	
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	Applicant(s)	
	Klaus SIMON	
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X							
Y							

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X	
Y	
Z	
AA	

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